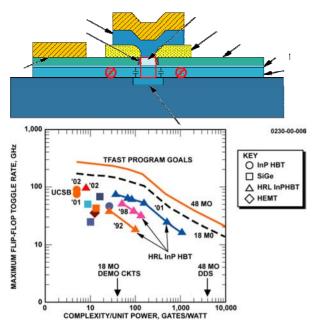
Graphic of Technology



Major Technical Accomplishments (since start of contract)

Demonstration of ion implantation with low sheet resistance (14  $\Omega$ /square) and subsequent MBE regrowth of device grade HBT material on large area substrate.

## Major Work Remaining to Completion of Contract

Demonstration of low parasitic HBT and static divider at 150 GHz.

## Goals, Objectives and Main Technical Approach

Demonstrate 250 nm Emitter Transistors  $f_t = 350 \text{ GHz}$ ,  $f_{max} = 400 \text{ GHz}$  (Phase IA) 150 GHz Static Flip-flop (Phase IA) 30 mW power per flip-flop at speed 20,000 HBT Integration level (Phase II) Minimize access resistances and parallel capacitance to an optimized intrinsic InP HBT transistor.

## Major Impact of Technology & Technology Transition Plan

3x clock rate, 10x power reduction and 10x integration level for high performance integrated circuits to enable advanced DoD system concepts.

Direct digital synthesis of X-band signals using conventional DDS architecture. Ability to realize digital synthesis of 40 GHz signals and above using  $\Delta\Sigma$  architecture. (5x the current DDS)